

NIL industrial day 2023



micro resist
technology

April 17 and 18, Vienna

Day 1 – April 17

CEST

09:00	11:00	Setting up of exhibition
11:00	12:30	Arrival of participants / exhibition

UAR INNOVATION NETWORK

	Affiliation	Speaker	Title
12:30	bmk, MRT, Profactor		Welcome

Session 1 – Session chair: Michael Hornung (GenlSys)



12:40	Applied Materials	Rami Hourani	Enabling High Performance Waveguide Combiners Using Nanoimprint Lithography
13:00	SÜSS MicroTec	Vijay Ramya Kolli	SUSS Imprint Solutions for High Quality Nano-optical Elements in AR/VR
13:20	Dispelix	Mikhail Omelyanovich	NIL Approach for Augmented Reality Industry
13:40	High RI Optics	Keiko Munechika	Filler-Free NIL Compatible Ultra-High Refractive Index Resins for Patterning Diffractive Optical Elements
14:00	micro resist technology	Arne Schleunitz	Industrial NIL Materials: Expectations and Solutions

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Event
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14:20	Coffee break / exhibition		
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Session 2 – Session chair: Pavel Kulha (Profactor)

15:00	Joanneum	Dieter Nees	 New Bio-Based Photo-Initiators for UV-Nano-Imprint Resins
15:20	imec	Eleonora Storace	Optimisation of nano-patterning for large-area high-density layouts
15:40	Inkron	Mikko Poutanen	Advances in spin coatable, and inkjetable high refractive index materials for nanoimprint processes
16:00	Profactor	Michael Haslinger	 Nanoimprinting of Micro and Nano-structures for Life Science Applications



16:20	Coffee break / exhibition		
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Session 3 – Session chair: Mirko Lohse (micro resist technology)

17:00	EVG	Andrea Kneidinger	Nanoimprint Lithography: Ideal Manufacturing Technology for Advanced Photonic Devices
17:20	NILT	Theodor Nielsen	Meta Optical Elements Product by Nanoimprint Lithography
17:40	WaveOptics (Snap Inc.)	Yury Stebunov	Production and Dimensional Metrology of AR Waveguides
18:00	Illumina	Tim Merkel	 NIL in Next Generation Sequencing



18:20	Social event, dinner		
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STENSBERG



Federal Ministry
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MEETING
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NILindustrialday 2023

April 17 and 18, Vienna

PROFACTOR

micro resist
technology

UAR INNOVATION
NETWORK

Day 2 – April 18

CEST

08:00	08:50			Exhibition, arrival of participants
	Affiliation	Speaker	Title	
08:50	MRT & Profactor		Welcome	
Session 4 – Session chair: Stefan Schrittwieser (AIT)				
09:00	Kioxia (online)	Tetsuro Nakasugi		Nanoimprint Lithography: Enabling Future Semiconductor Manufacturing to be Energy Efficient
09:20	Wearoptimo (online)	Vignesh Suresh		Manufacturing Microwearables for Continuous Health Monitoring
09:40	Silicon Austria Labs	Mustapha Chouiki		Nanofabrication for MEMS Technology
10:00	Morphotonics	Sander Kommeren		Large-Area Nanoimprint: Challenges and Opportunities
10:20	SÜSS MicroOptics	Patrick Heissler		Enabling the Volume: Imprinted Micro-Optics for Automotive Applications
10:40				Coffee break / exhibition
Session 5 – Session chair: James Watkins (Univ. Mass. Amherst)				
11:20	SCIL	Marc Verschuuren		Nanometer-Accurate Nano-Photonic Optical Structures in Inorganic Materials with Sub-Micron Overlay Accuracy
11:40	Fraunhofer IOF	Robert Leitel		Selective Molding of Microoptics
12:00	scia Systems	Philipp Böttger		Manufacturing of Slanted Surface Relief Gratings: Flexibility in Trench Design by Ion Beam Trimming
12:20	SINTEF	Christopher Dirdal		MEMS-tunable Metasurfaces Using Thin-Film PZT, Offering Large Displacements at Low Voltages
12:40	Stensborg	Oskar Darselius Berg		Energy Efficient Coloration of Solar Panels
13:00	MRT & Profactor			Final announcements
13:10				Lunch
14:30				End of exhibition and of NILindustrialday 2023

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